Abstracts

Measurements of field distributions and scattering parameters in multiconductor structures using an electric field probe

Yingjie Gao and I. Wolff. "Measurements of field distributions and scattering parameters in multiconductor structures using an electric field probe." 1997 MTT-S International Microwave Symposium Digest 3. (1997 Vol. III [MWSYM]): 1741-1744.

A simple electric coaxial field probe for application in the 0.05-20 GHz band has been developed, which can measure not only the magnitude and the phase of the microwave field distribution inside multiconductor RF and microwave circuits, but also the scattering parameters at arbitrary reference planes inside the structures can be measured using this technique.

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